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*#7/A entered in part*  
*4-23-03*  
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PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

Yoshikazu MIYAJIMA et al.

Application No.: 10/022,506

Filed: December 20, 2001

For: EXPOSURE APPARATUS, DEVICE  
MANUFACTURING METHOD, SEMICONDUCTOR  
MANUFACTURING FACTORY, AND EXPOSURE  
APPARATUS MAINTENANCE METHOD

)  
: Examiner: R. Fuller  
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: Group Art Unit: 2851  
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:  
) April 14, 2003  
) (Monday)  
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The Commissioner for Patents  
Washington, D.C. 20231

AMENDMENT

Sir:

INTRODUCTORY COMMENTS

This Amendment has been prepared in accordance with the Revised Format established by the U.S. Patent and Trademark Office, as permitted in the Pre-OG Notice dated February 4, 2003, and entitled "Amendments in a Revised Format Now Permitted."

In response to the Official Action dated January 13, 2003, please amend the above-identified application as follows:

4/16/2003 DEMANDU1 00000113 10022506

01 50:1201  
02 15:1202

840.00 OF  
378.00 OF